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Atty. Dkt. No. 039153-0310 (F0797)

*Yes
Changed*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Calvin T. Gabriel et al.

Title: PROCESS FOR IMPROVING
THE ETCH STABILITY OF
ULTRA-THIN PHOTORESIST

Appl. No.: 09/819,552

Filing Date: 3/28/2001

Examiner: Binh X. Tran

Art Unit: 1765

CERTIFICATE OF FACSIMILE TRANSMISSION I hereby certify that this paper is being facsimile transmitted to the United States Patent and Trademark Office, Alexandria, Virginia on the date below. Kathryn J. Berg (Printed Name) Kathryn J. Berg (Signature) July 6, 2004 (Date of Deposit)

AMENDMENT AND REPLY UNDER 37 CFR 1.116

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

This communication is responsive to the Final Office Action dated May 4, 2004,
concerning the above-referenced patent application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2
of this document.

Remarks/Arguments begin on page 6 of this document.

Please amend the application as follows:

07/13/2004 RHOLLAND 00000001 061447 09819552

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001.1652243.1

Application No. 09/819,552